

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Toshiaki ONO, et al.**

Serial No.: **Not Yet Assigned**

Filed: **June 20, 2001**

For: **METHOD OF MANUFACTURING EPITAXIAL WAFER AND METHOD OF
PRODUCING SINGLE CRYSTAL AS MATERIAL THEREFOR**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

June 20, 2001

Sir:

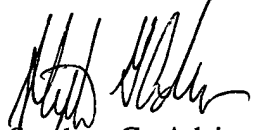
In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

Copies of the references are enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge

Deposit Account No. 01-2340.

Respectfully submitted,
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Enclosures: PTO-1449; References (4)

